

ABSTRACT

The present invention provides a machine learning operation system (101) for performing vision inspection on semiconductor device, comprising of a plurality of semiconductor vision inspection equipment (105) configured to communicate with a centralized workstation (107) through at least one network switch (109). The present invention also provides a method for performing vision inspection on semiconductor device, using said system, whereby said method implements machine learning model training using collected datasets and deployment of trained machine learning model to said semiconductor vision inspection equipment (105).

10 (Fig. 2)